



FTW

PATENT
Attorney Docket No. 07553.0044-00

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| | | |
|-----------------------------|---|------------------------|
| In re Application of: |) | |
| |) | |
| Hideki TANAKA |) | Group Art Unit: 2878 |
| |) | |
| Application No.: 10/644,745 |) | Examiner: J. Lee |
| |) | |
| Filed: August 21, 2003 |) | |
| |) | |
| For: PLASMA LEAK MONITORING |) | Confirmation No.: 6213 |
| METHOD, PLASMA |) | |
| PROCESSING APPARATUS AND |) | |
| PLASMA PROCESSING |) | |
| METHOD |) | |

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE TO OFFICE ACTION UNDER 37 C.F.R. §1.111

In response to the Office Action mailed September 20, 2006, the time period for response to which extends to December 20, 2006, Applicants respectfully request reconsideration of the above-identified application in view of the following remarks.

REMARKS

I. Status and Disposition of the Claims

Claims 1-12 are pending. No claims are amended herein.

Claims 1, 3-5, 7-9, 11 and 12 are allowed by the Examiner. Office Action at 2-3.

Applicant thanks the Examiner for the indication of allowable subject matter. However, claims 2, 6 and 10 are rejected by the Examiner under 35 U.S.C. §102(e) as being